

10/500654

DT15 Rec'd PCT/PTO 02 JUL 2004

**PATENT APPLICATION**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

PCT/FR02/04588

Docket No: Q82315

Michel PUECH, et al.

Appln. No.: Not Assigned

Confirmation No.: Not Assigned

Group Art Unit: Not Assigned

Filed: July 02, 2004

Examiner: Not Assigned

For: A METHOD AND APPARATUS FOR ANISOTROPICALLY ETCHING SILICON  
WITH A HIGH ASPECT RATIO

**PRELIMINARY AMENDMENT**

**MAIL STOP AMENDMENT**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Prior to examination, please amend the above-identified application as follows on the  
accompanying pages.

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